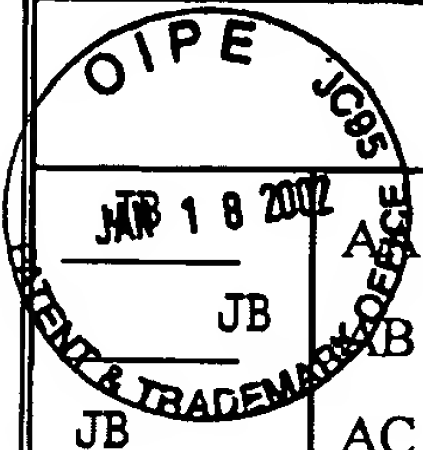


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	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

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	JB	52-117567 ✓	10/03/77	JAPAN	ABSTRACT
	AC	57-072326 ✓	05/06/82	JAPAN	ABSTRACT
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	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

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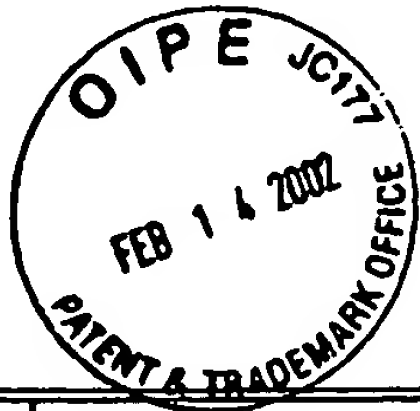
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JB	6,125,522	Nakasuji	10/03/00			11/12/96
JB	6,087,667	Nakasuji et al.	07/11/00			09/30/97
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<div data-bbox="174 699 458 1042"> </div> <div data-bbox="283 1142 338 1185">JB</div> <div data-bbox="207 1185 360 1213">-----</div>	BK ✓ BL ✓ BM ✓ BN ✓	<p><i>Multi-Beam Concepts for Nanometer Devices</i>, B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.</p> <p><i>An electron-beam inspecting system for x-ray mask production</i>, P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.</p> <p><i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i>, W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.</p> <p><i>Table 5-1 Work Function in Metals</i> page 116.</p>
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	Applicant(s): Mamoru NAKASUJI et al.	
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<u>JB</u>	AF	2000-100369 ✓	4/7/00	Japan	Yes/Abstract
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<u>JB</u>	AJ	10-125271 ✓	5/15/98	Japan	Yes/Abstract
<u>JB</u>	AK	11-233062 ✓	8/27/99	Japan	Yes/Abstract
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